



Docket No.: 543822005300
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Steven WANG et al.

Application No.: 10/812,412

Confirmation No.: 1275

Filed: March 30, 2004

Art Unit: 2814

For: METHOD FOR PRODUCING A DEEP
TRENCH CAPACITOR IN A
SEMICONDUCTOR SUBSTRATE

Examiner: N. W. Ha

OK X to 1/22/07
R/K

AMENDMENT AFTER FINAL ACTION UNDER 37 C.F.R. 1.116

MS AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

This is in response to the final Office Action dated June 28, 2006. Filed herewith is a Petition and fee for a three (3) month(s) extension of time, thereby extending the deadline for response to December 28, 2006. Accordingly, this response is timely filed. Reconsideration and allowance of the pending claims, as amended, in light of the remarks presented herein are respectfully requested.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.